

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-2373		PRIORITY SERIAL NO. 10/261,735	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Garol J. Dordorian			
				PRIORITY FILING DATE September 30, 2002		PRIORITY GROUP 1762	

  

U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
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7	AM	EP 0794568	10/1997	Europe	—	—	
7	AN	05-251339	09/1993	Japan	—	—	
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7	AR	Kiyoko et al., Patent Abstract Application No. 04-024917 (JP 9224917, 09/1993), "Semiconductor Substrate and its Manufacture."	
7	AS	Ritala, et al., "Atomic Layer Epitaxy - A Valuable Tool for Nanotechnology?" Nanotechnology, Vol. 10, No. 1, pps. 19-24, March 1999.	
7	AT	George, et al., "Surface Chemistry for Atomic Layer Growth", Journal of Physical Chemistry, Vol. 100, No. 31, pps. 13121-13131, August 1, 1996.	
7	AU	Suntola, "Atomic Layer Epitaxy", Handbook of Crystal Growth, Vol. 3, Chapter 14, pps. 602-663.	
7	AV	Vernon, S.M., "Low-cost, high-efficiency solar cells utilizing GaAs-on-Si technology." Dialog Abstract of Report No. NREL/TP-451-5353; 04/1993.	

  

EXAMINER <i>Michael Barr</i>	DATE CONSIDERED <i>2/19/04</i>
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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7	AS		Aarik et al, "Effect of Growth Conditions on Formation of TiO <sub>2</sub> -II Thin Films in Atomic Layer Deposition Process", Journal of Crystal Growth, Vol. 181, August 1997, pp. 259-284.						
7	AT		Skarp, "ALE-Reactor for Large Area Depositions", Applied Surface Science, vol. 112, March 1997, pp. 251-254.						
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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2373	PRIORITY SERIAL NO. 10761,735	
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	AE					
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7	AD	6,235,571	05/2001	Doan	—	—	
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	AL						
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7	AP		Aarik, et al, "Control of Thin Film Structure by Reactant Pressure in Atomic Layer Deposition of TiO <sub>2</sub> ," Journal of Crystal Growth, 169 (1996) pgs. 496-502				
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